

## United States Patent and Trademark Office

Rih Data Shoot

**CONFIRMATION NO. 3979** 

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SERIAL NUMB 10/709,980		FILING DATE 06/10/2004 RULE		CLASS 117	GROUP ART UNIT 1722		ATTORNEY DOCKET NO. TOPP0016USA			
APPLICANTS										
Ching-Wei Lin, Tao-Yuan Hsien, TAIWAN;										
" CONTINUING DATA """"""""""""""""""""""""""""""""""										
** FOREIGN APPLICATIONS ************************************									i	
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 07/15/2004										
Foreign Priority claimed  35 USC 119 (a-d) conditions  yes no Met after met  Verified and Lakinowledged  Examiner's Signature Initials  STATE OF COUNTRY  TAIWAN					SHE	SHEETS TOTA		۹L ·	INDEPENDENT	
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ADDRESS 027765 NORTH AMERICA INTERNATIONAL PATENT OFFICE (NAIPC) P.O. BOX 506 MERRIFIELD , VA 22116										
TITLE METHOD OF FORMING A THIN FILM TRANSISTOR BY UTILIZING A LASER CRYSTALLIZATION PROCESS										
FILING FEE FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUN RECEIVED No for following: 770						1.18 Fees (Issue)				
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